

[illegible][illegible][illegible]

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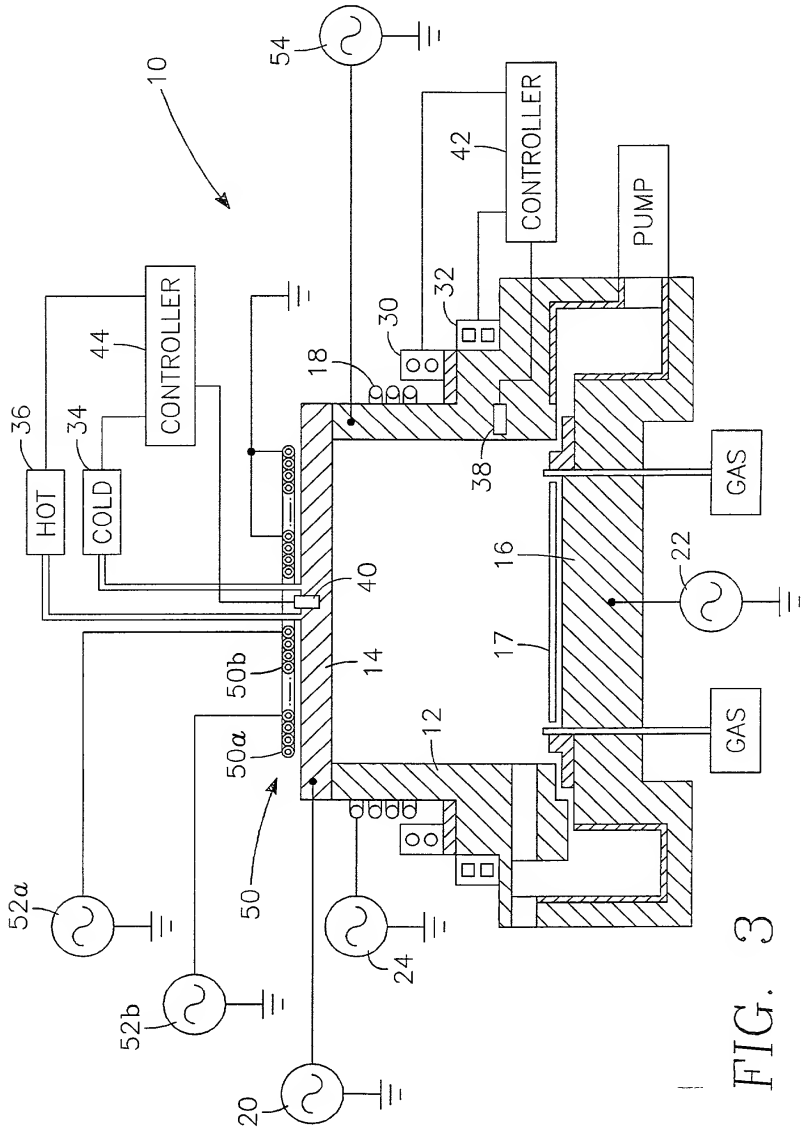


FIG. 3

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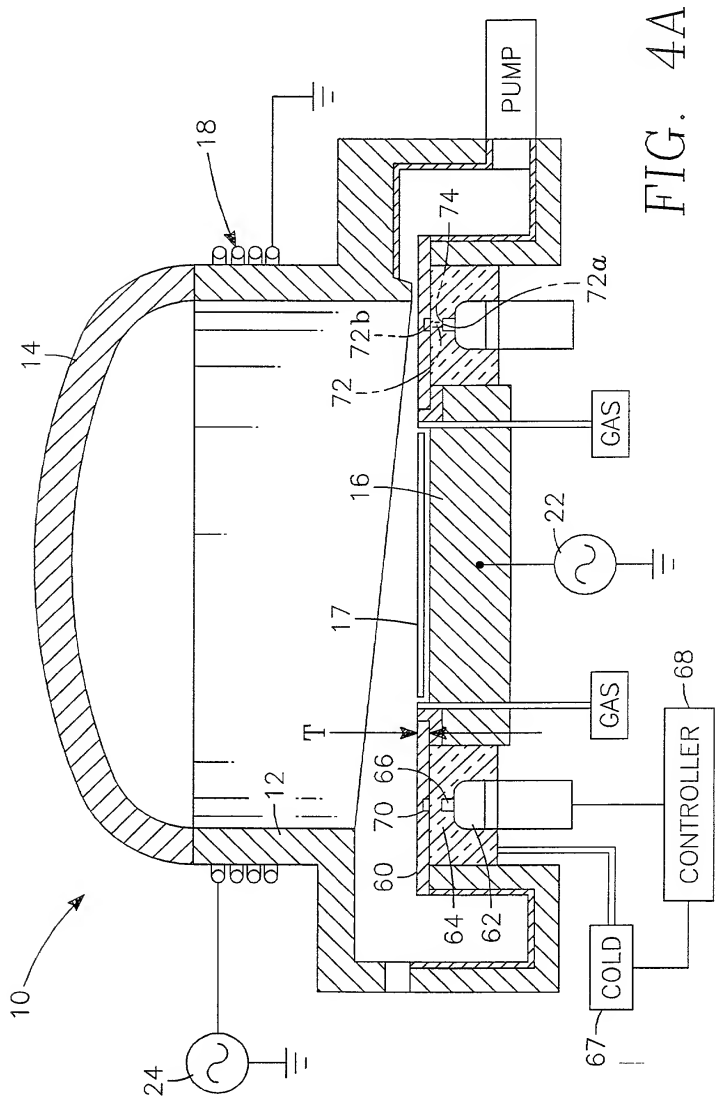


FIG. 4A

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FIG. 4A

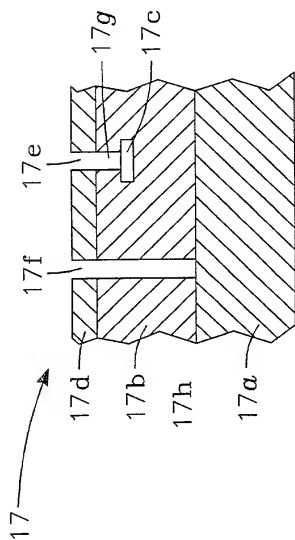


FIG. 4B

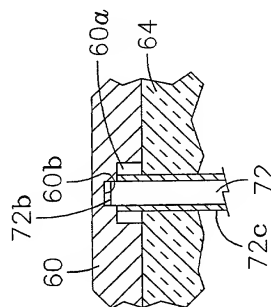


FIG. 4C

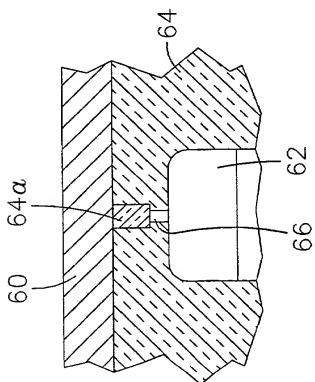


FIG. 4D

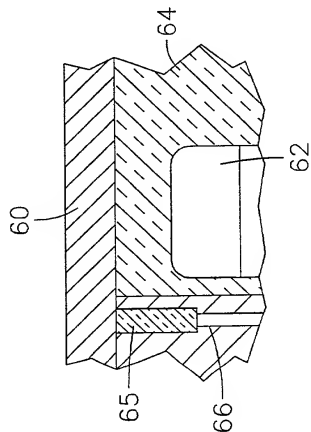


FIG. 4E

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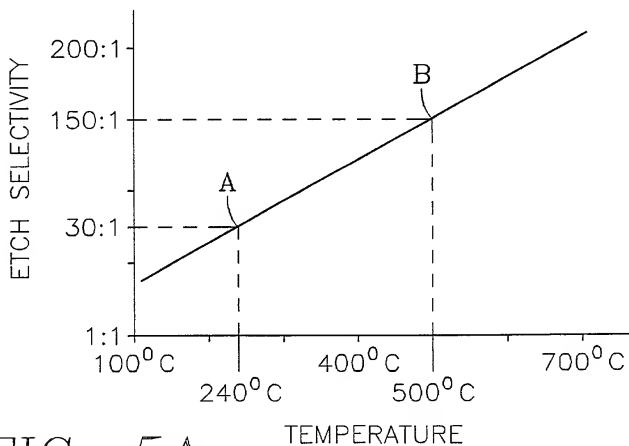


FIG. 5A

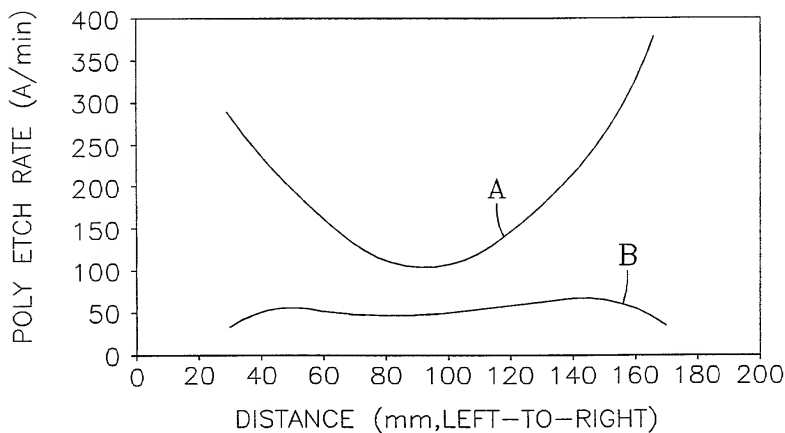


FIG. 5B

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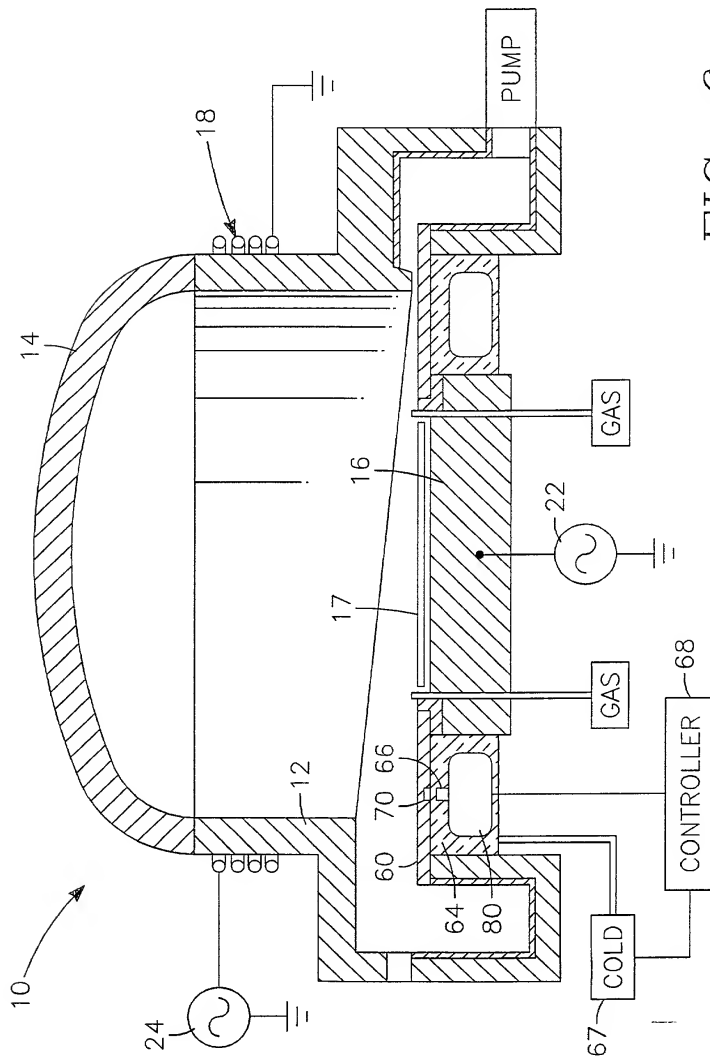


FIG. 6

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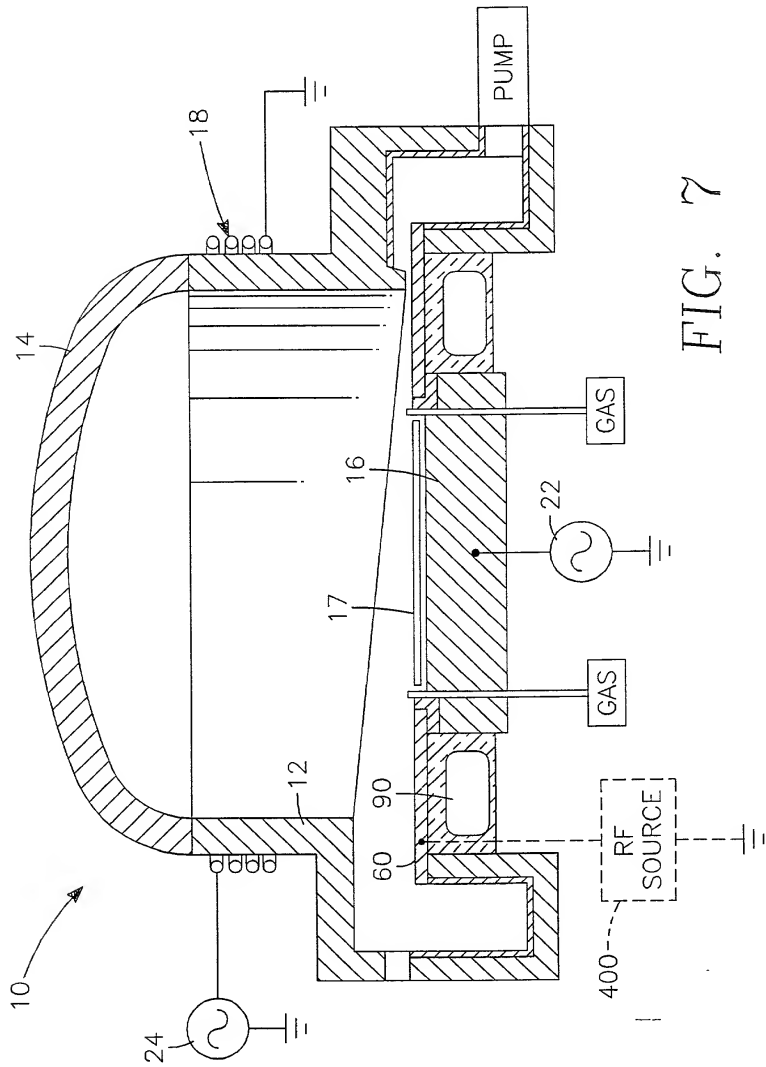


FIG. 7

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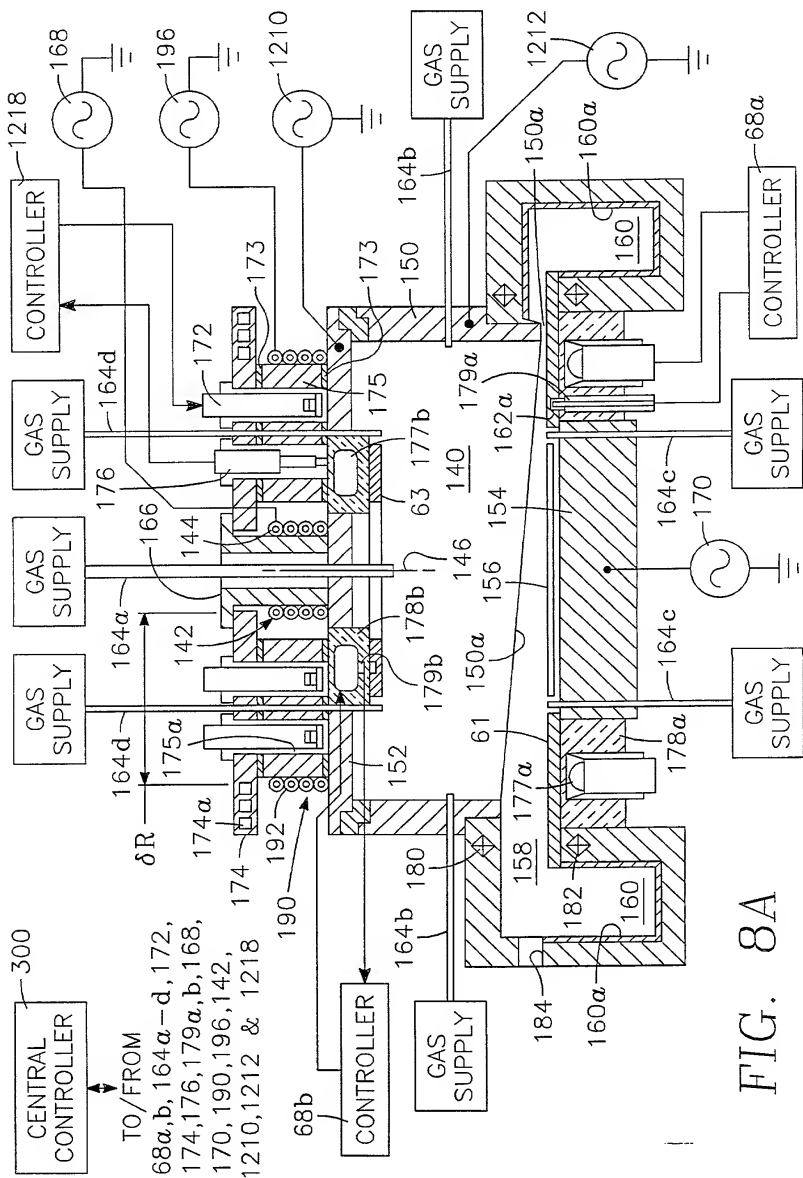


FIG. 8A



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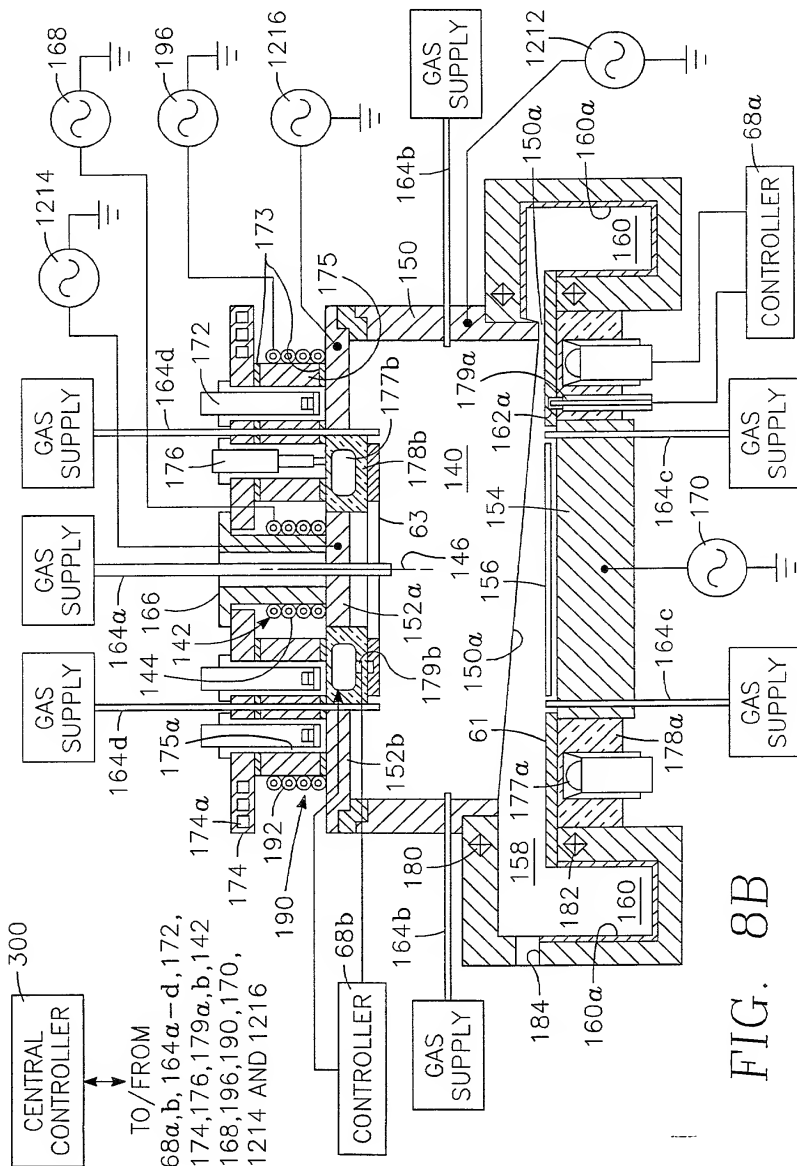


FIG. 8B

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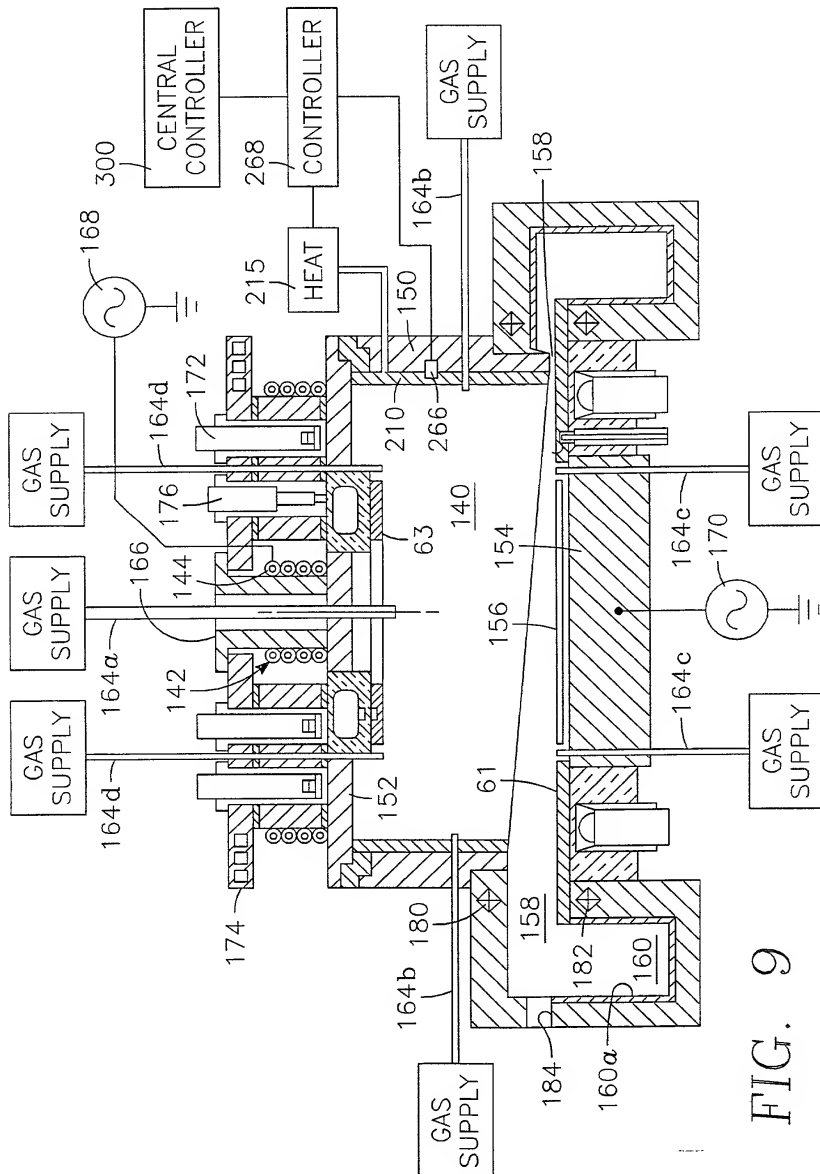


FIG. 9

LOW CEILING TEMPERATURE PROCESS FOR A PLASMA REACTOR WITH  
HEATED SOURCE OF A POLYMER-HARDENING PRECURSOR MATERIAL  
ATTORNEY DOCKET 306 C09

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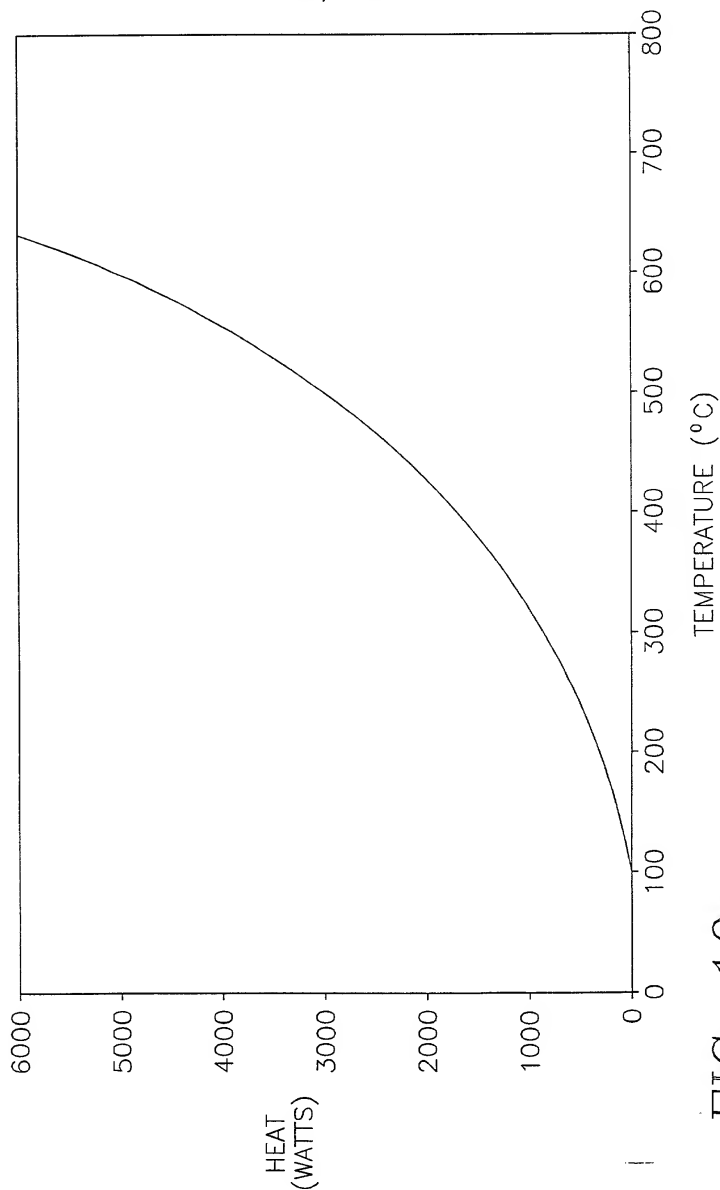


FIG. 10

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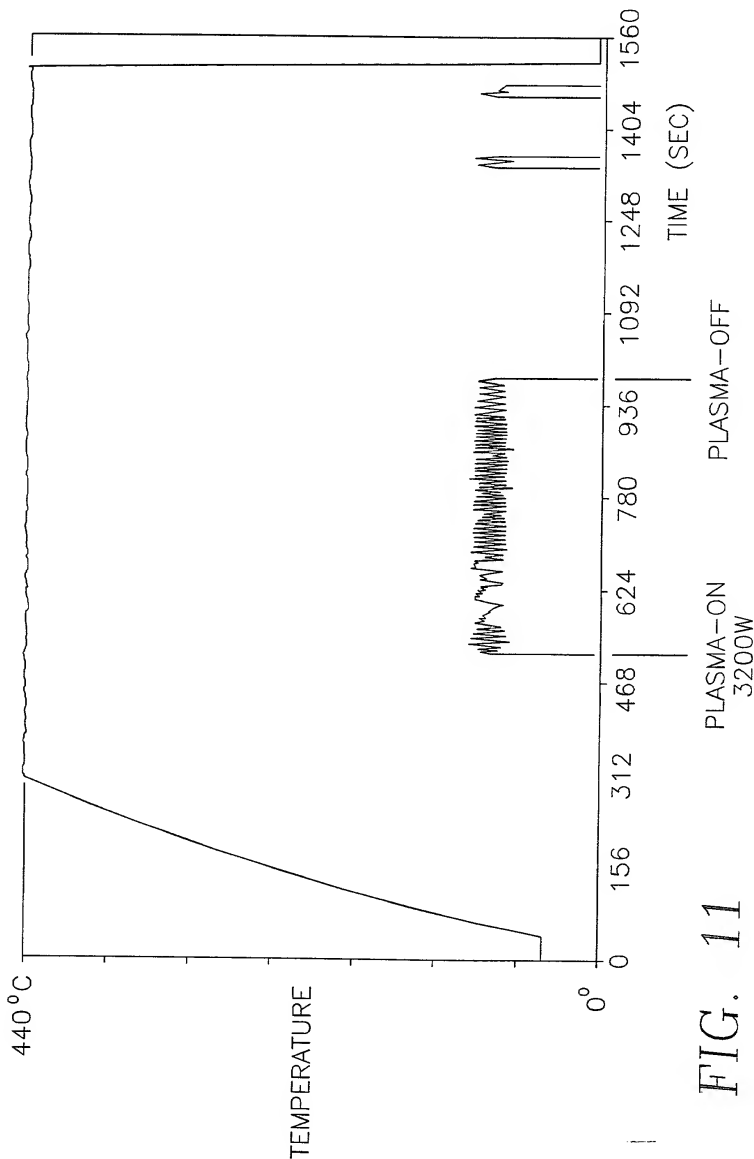


FIG. 11

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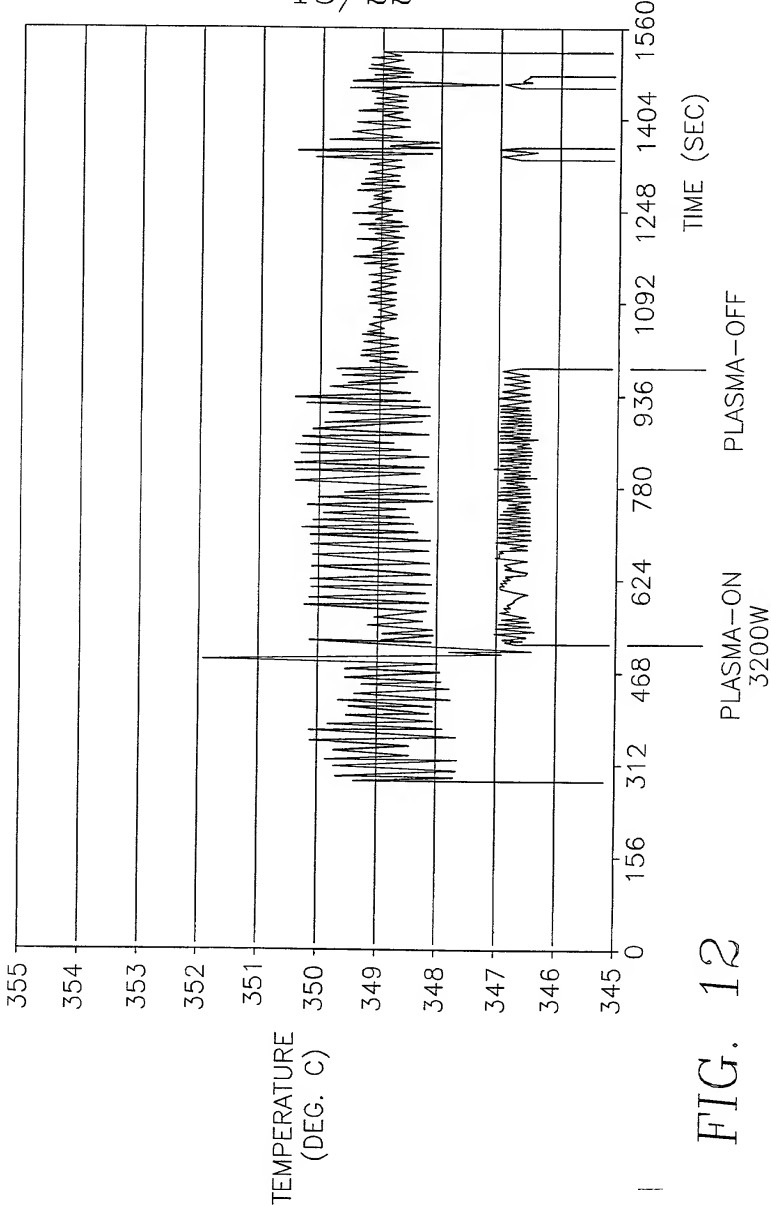
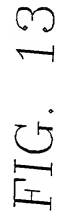


FIG. 12

TOP SECRET 26630001



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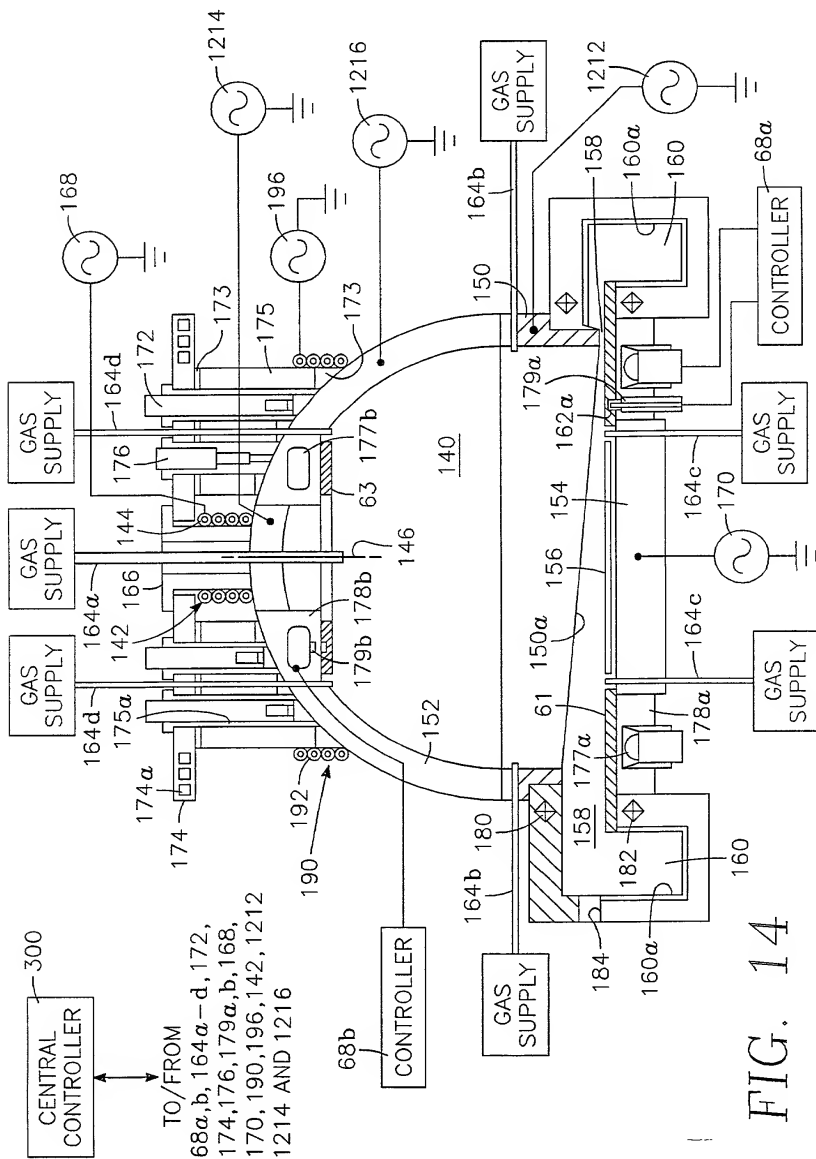


FIG. 14

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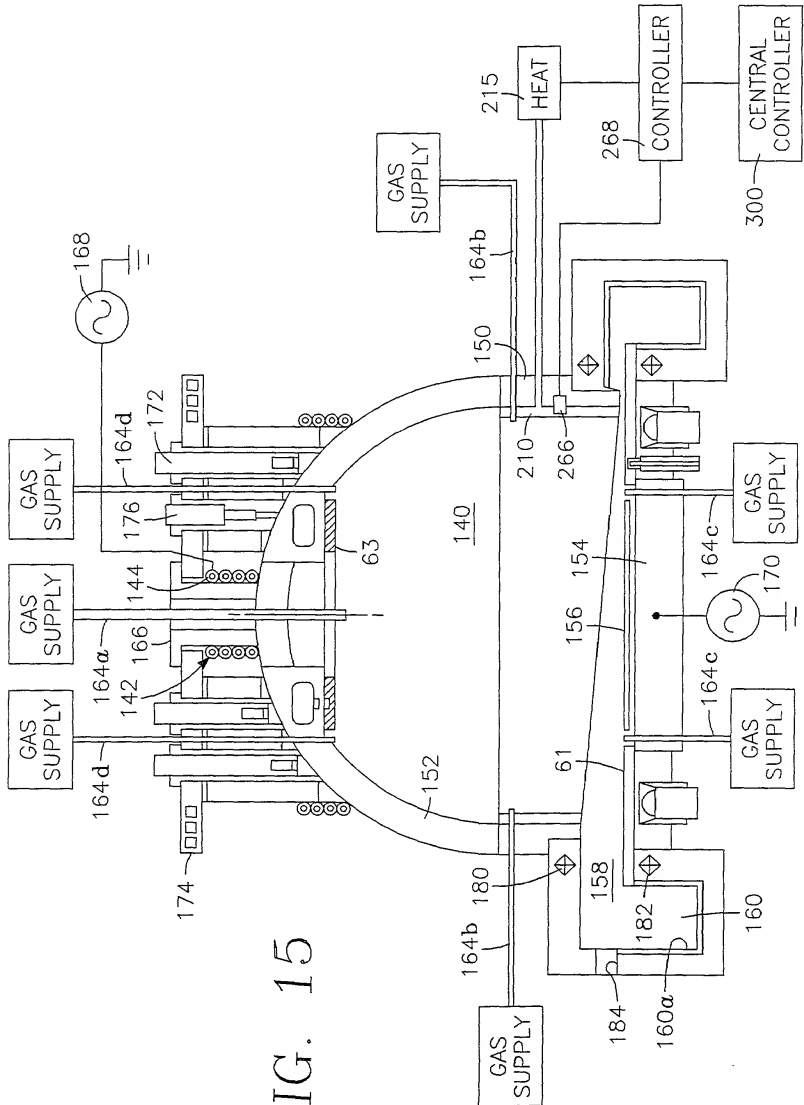
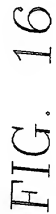
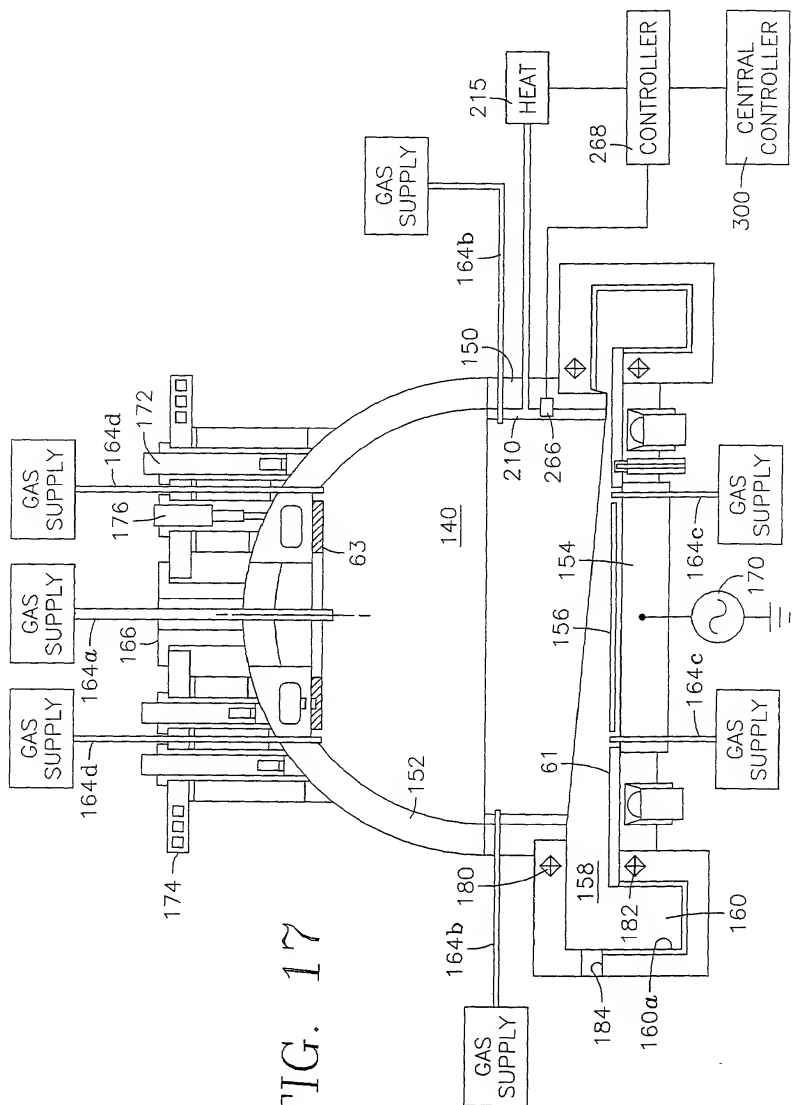
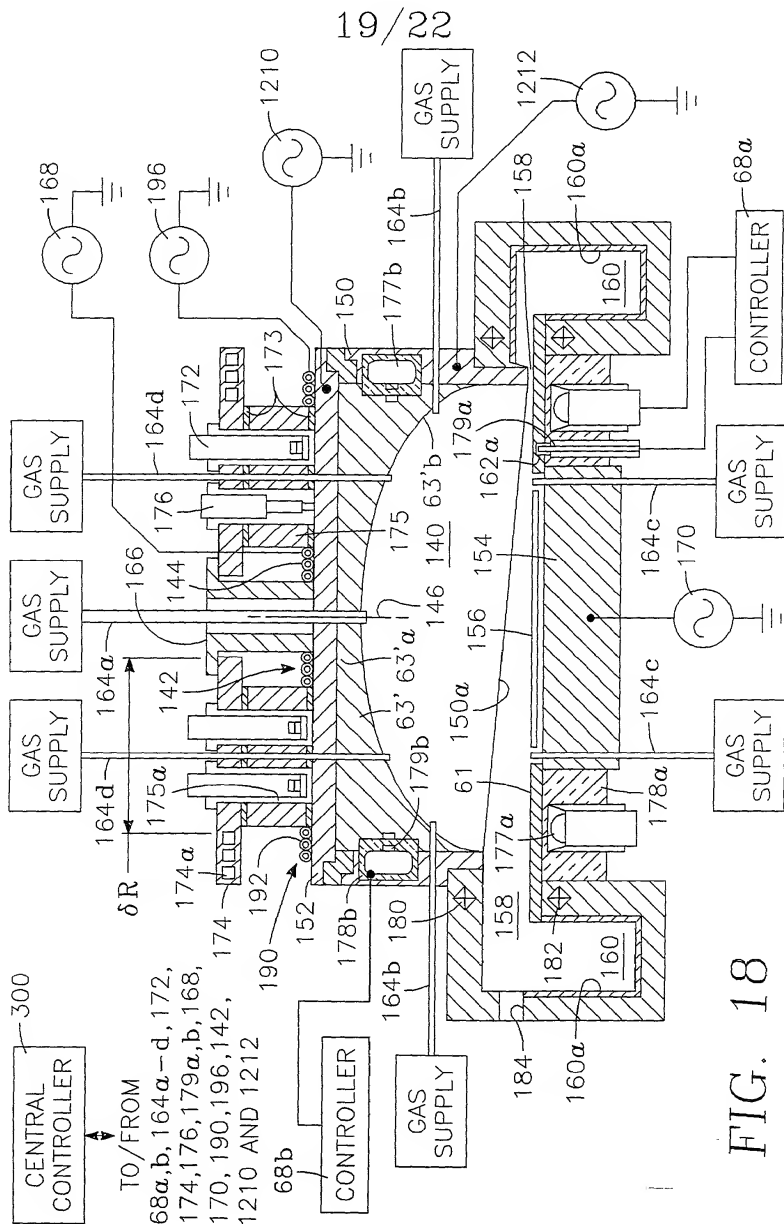


FIG. 15









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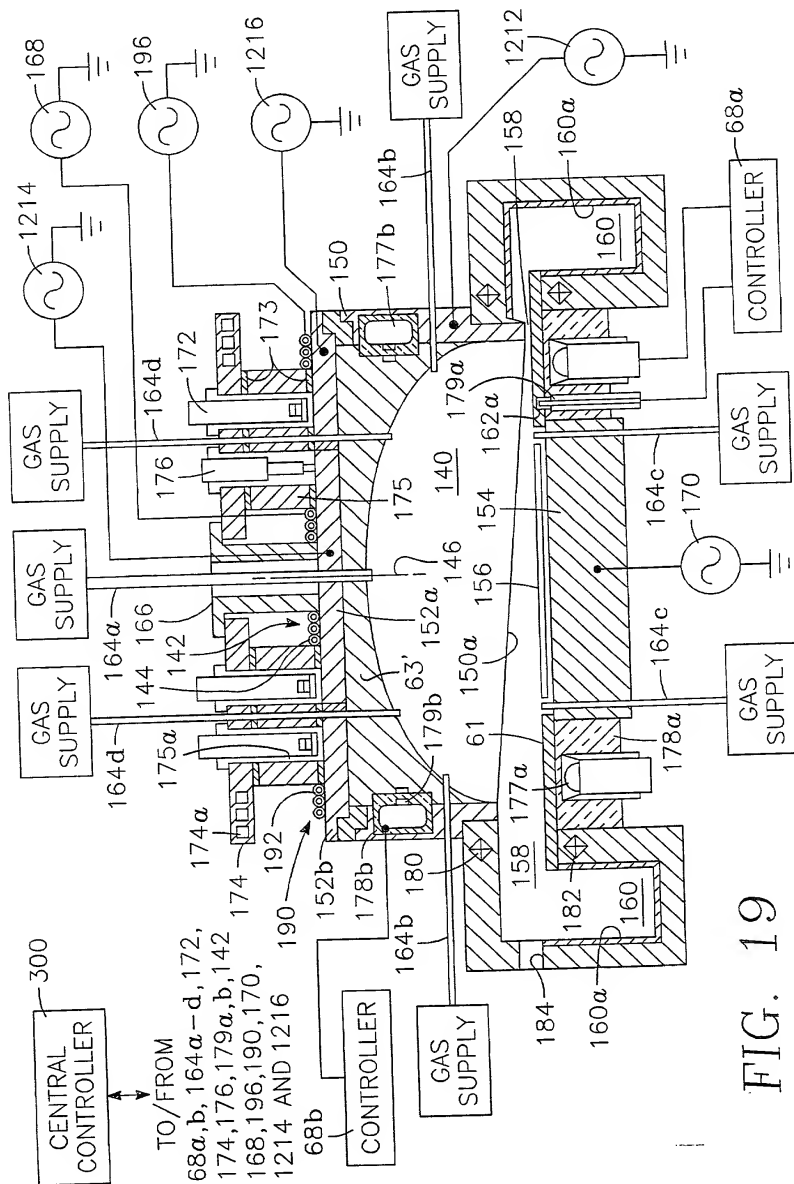


FIG. 19

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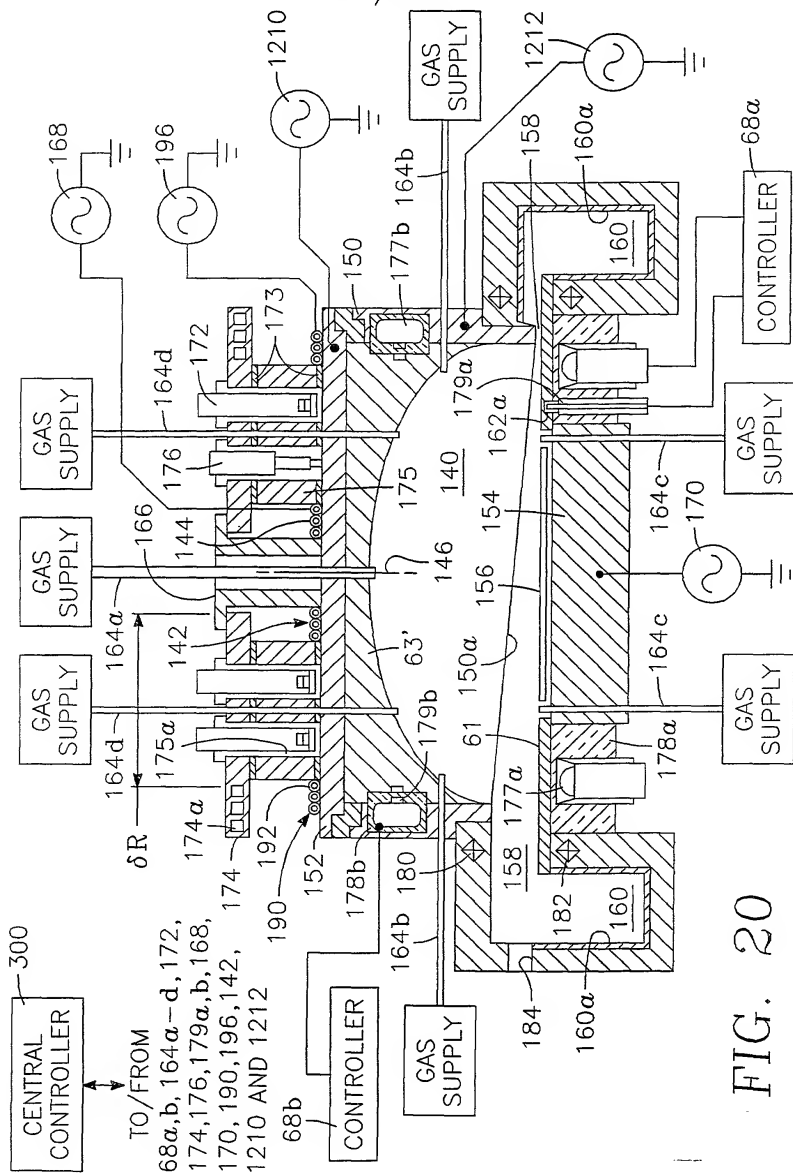


FIG. 20

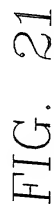


FIG. 21